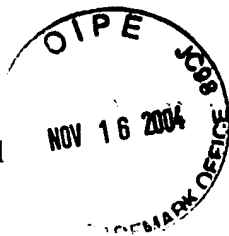


IFW

Docket No.: 50432-601



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of	:	Customer Number: 20277
	:	
Minh Van NGO, et al.	:	Confirmation Number: 3500
	:	
Application No.: 10/617,451	:	Group Art Unit: 2812
	:	
Filed: July 11, 2003	:	Examiner: Lindsay Jr, Walter Lee
	:	
For: PECVD SILICON-RICH OXIDE LAYER FOR REDUCED UV CHARGING :		

AMENDMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

The following Amendment and Remarks are submitted in response to the Office Action dated September 22, 2004.